5/19/99

S/N 09/135.413

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Leonard Forbes et al.

Serial No.: Filed:

Title:

09/135,413

August 14, 1998

Docket: 303.354US2 DEAPROM HAVING AMORPHOUS SILICON CARBIDE GATE

**INSULATOR** 

AMENDMENT AND RESPONSE

sistant Commissioner for Patents TENDEWashington, D.C. 20231

Tle = A 29/97

1d the above
6275668 In response to the Office Action mailed February 23, 1999, please amend the above identified patent application as follows:

IN THE TITLE

Please delete the title and replace it with the following: -- Method For Operating A DEAPROM Having An Amorphous Silicon Carbide Gate Insulator--.

IN THE SPECIFICATION

Please amend the specification by deleting lines 5-18 on page 1 of the originally filed application, beginning with the heading "Cross Reference To Related Applications."

On page 19, lines 26-27, please replace "serial number " with --serial number

08/903,453--.

MAY 2 5 1000

IN THE CLAIMS

Please cancel claims 25-27 and 39-42.

Please amend the claims as follows:

TECHNOLOGY CENTER 2800

PATENT

Examiner: Viet Q. Nguyen

Group Art Unit: 2818

(Amended) A method of using a floating gate transistor having a floating gate electrode and an adjacent amorphous silicon carbide (a-SiC) gate insulator between the floating gate electrode and a substrate, the method comprising:

storing data by changing [the] a charge of the floating gate electrode; reading data by detecting a current between a source and a drain in the substrate; and

35/21/1999 TTRRM1